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(71) Applicant (for all designated States except US): **ADVANCED TECHNOLOGY MATERIALS, INC.** [US/US]; Margaret Chappuis, 7 Commerce Drive, Danbury, CT 06810 (US).

(72) Inventors; and

(75) Inventors/Applicants (for US only): **DIMEO, Frank, Jr.** [US/US]; 27 Crows Nest Lane, 19G, Danbury, CT 06810 (US). **CHEN, Philip, S.H.** [US/US]; 26 Budd Drive, Bethel, CT 06801 (US). **CHEN, Ing-Shin** [CN/US]; 6 Sleepy Hollow Drive, Danbury, CT 06810 (US). **NEUNER, Jeffrey, W.** [US/US]; 141 Old Hawleyville Road, Bethel, CT 06801 (US). **WELCH, James** [US/US]; 3 Lancaster Road, New Fairfield, CT 06812 (US).

(74) Agent: **MARGARET CHAPPUIS**; ADVANCED TECHNOLOGY MATERIALS, INC., 7 Commerce Drive, Danbury, CT 06810 (US).

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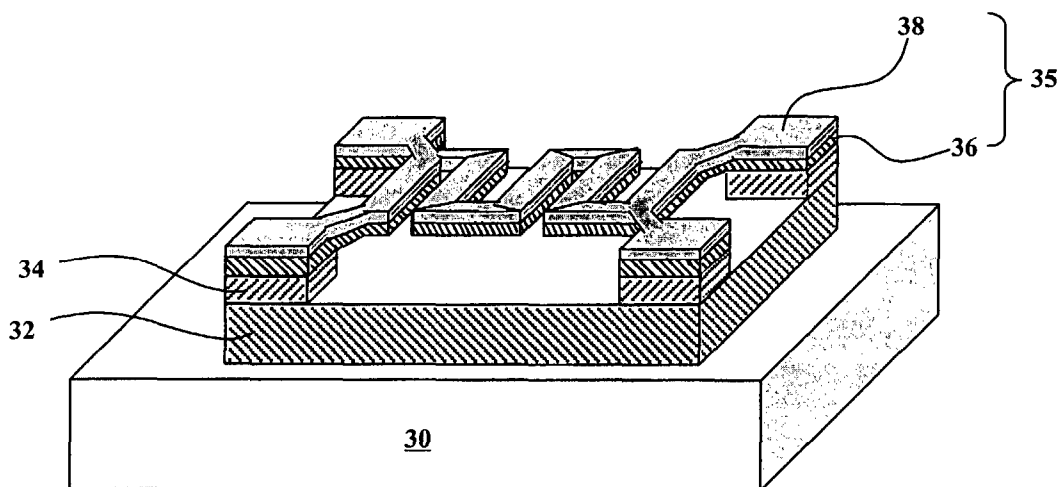
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(54) Title: **NICKEL-COATED FREE-STANDING SILICON CARBIDE STRUCTURE FOR SENSING FLUORO OR HALOGEN SPECIES IN SEMICONDUCTOR PROCESSING SYSTEMS, AND PROCESSES OF MAKING AND USING SAME**



(57) Abstract: A (MEMS)-based gas sensor assembly for detecting a fluorine-containing species in a gas containing same, e.g., an effluent of a semiconductor processing tool undergoing etch cleaning with HF, NF₃, etc. Such gas sensor assembly in a preferred embodiment comprises a free-standing silicon carbide support structure having a layer of a gas sensing material, preferably nickel or nickel alloy, coated thereon. Such gas sensor assembly is preferably fabricated by micro-molding techniques employing sacrificial molds that are subsequently removable for forming structure layers.

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